

**IN THE UNITED STATES PATENT AND TRADEMARK OFFICE**

Application Serial No. .... 10/728,532  
Confirmation No. .... 8286  
Filing Date ..... December 5, 2003  
Inventor..... John F. Van Itallie et al.  
Assignee..... Micron Technology, Inc.  
Group Art Unit..... 1756  
Examiner ..... Kathleen Duda  
Attorney's Docket No. ..... MI22-2458  
Customer No. ..... 021567  
Title: Photolithographic Methods Of Using A Single Reticle To Form Overlapping Patterns

**RESPONSE TO JUNE 1, 2006 FINAL OFFICE ACTION**

Response Filed After Final Action

To: Mail Stop AF  
Commissioner for Patents  
P.O. Box 1450  
Alexandria, VA 22313-1450

From: David G. Latwesen (Tel. 509-624-4276; Fax 509-838-3424)  
Wells St. John P.S.  
601 W. First Avenue, Suite 1300  
Spokane, WA 99201-3828

**AMENDMENTS**